

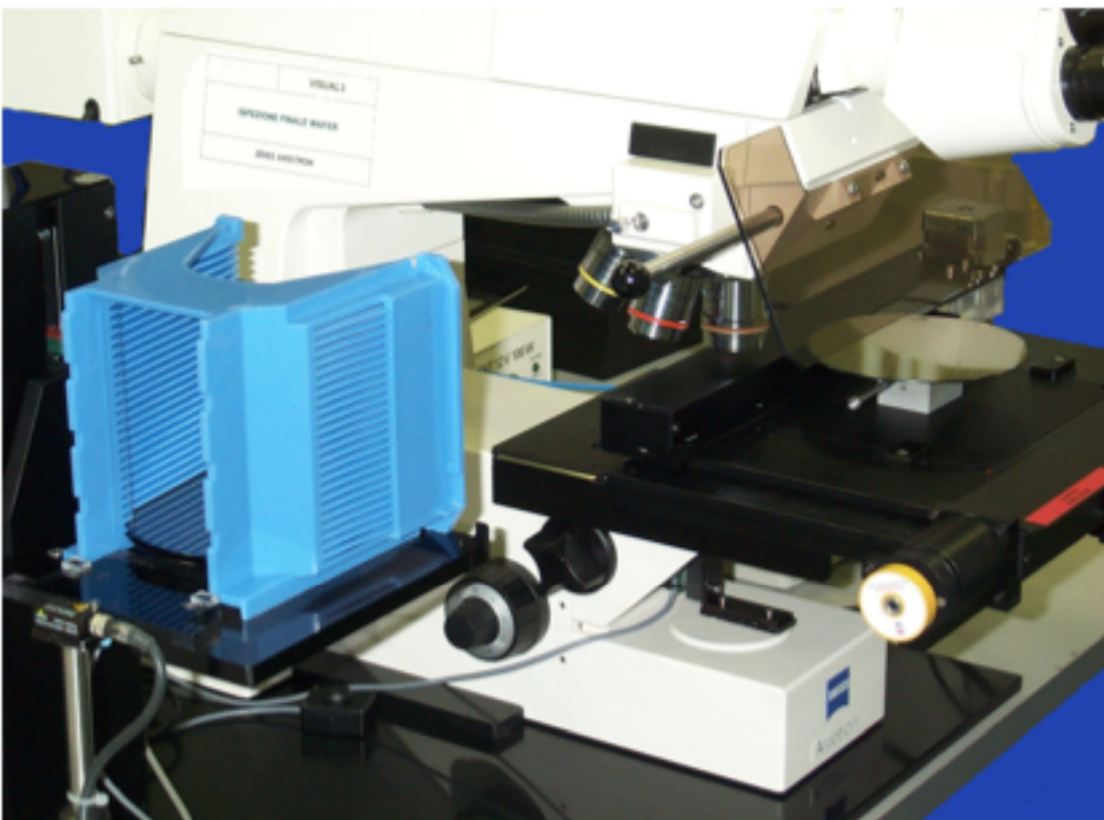
Semicon Synapsis

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Proteus Autoloader

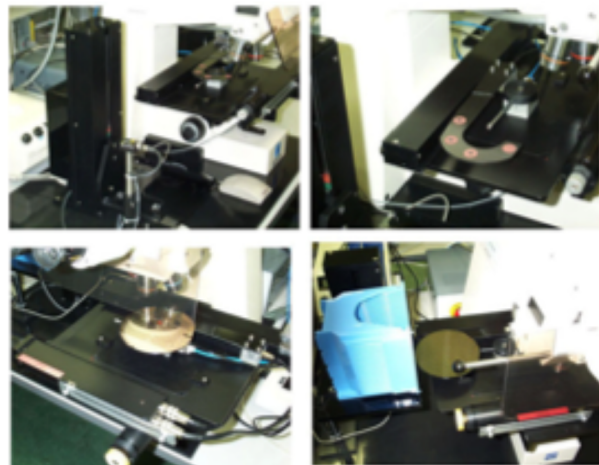
Simple microscope loader for wafers



Simple and smart

The new Proteus simple loader is an innovative approach to microscope wafer automatic loading. It has been especially studied to give an answer to microscope loading when handling can be critical, such as when wafers are thin, since handling is really reduced to the minimum possible, thus reducing the possibility of damaging wafers.

Proteus Autoloader includes an extraction tool which is directly mounted over the microscope inspection table, allowing the microscope to directly take wafers from cassette (a stand alone version for standard microscope interfacing is also available)



Specifications	
Wafer size	150 - 200 mm - single or multi size
Wafer thickness	170 – 1200 µm
Clean room compatibility	Class 10 clean room compatible
Control	Computer control with touch screen operator interface
Type of inspection	Micro inspection
Inspection mode	Sequential, sampling or statistical access
Centering	Pre centering on wafer edge (no alignment of flat/notch)
Compatible microscopes	Astel MX-R - Other semiconductor inspection microscopes
Footprint	W 800 x D 700 x H 650 (including Back unit in up position)
Cassette mapping	Laser sensor with thin wafer detection capability
Facilities	AC 220 - 240 V - 3,5 A 50 /60 Hz Vacuum - 60 to -90 KPa - 10 l/min Compressed air or nitrogen - 6 bar

(Specifications are subject to change without any obligation on the part of manufacturer)

